

IN THE CLAIMS:

1. (Currently Amended) A method for manufacturing plasma display panels (~~PDP~~) (PDPs) including comprising:

a ~~step of~~ forming a film on a substrate in an evaporating room, ~~with~~ the substrate held by ~~a substrate holder~~ one of a plurality of substrate holders, and

repeatedly using the plurality of substrate holders to form film on a substrate, such that when the film is formed on a substrate, at least one substrate holder in the evaporating room is coated with film from forming the film on the substrate, and at least one holder in the evaporating room is not coated with said film.

~~wherein when a film is formed, the substrate holder is repeatedly used, and in the step of forming a film on a substrate, a substrate holder attached with the film due to repeated use co-exists with another substrate holder, from which the film attached is removed, in an evaporating room.~~

2. (Currently Amended) The method for manufacturing ~~PDP~~ PDPs as defined in claim 1, wherein the evaporating room contains a greater number of substrate holders ~~attached~~ coated with the film due to repeated use than ~~a number of substrate holders from which the film attached is removed~~ not coated with said film.

3. (Canceled)

4. (Currently Amended) The method for manufacturing PDP as defined in claim ~~3~~ 5, wherein the plurality of elements ~~include~~ comprises a frame retaining the substrate and a dummy substrate retained by another frame, and the film ~~attached~~ is removed from the

dummy substrate.

5. (New) A method for manufacturing plasma display panels (PDPs) comprising:
forming a film on a substrate in an evaporating room, the substrate being held by one of a plurality of substrate holders, the substrate holders comprising a plurality of elements,
and

repeatedly using the plurality of substrate holders, such that when the film is formed on a substrate, at least one substrate holder in the evaporating room is coated with film from forming the film on the substrate, and at least one holder in the evaporating room comprises elements not coated with said film.

6. (New) The method according to claim 5, wherein the elements not coated with said film comprise at least one of a frame retaining the substrate, a dummy substrate, and a frame retaining the dummy substrate.